

UNITED STATES
PATENT AND TRADEMARK OFFICE



Patent Public Advisory Committee Quarterly Meeting

International Update Global Dossier

Shira Perlmutter

Chief Policy Officer and Director for International Affairs

Mark Powell

Deputy Commissioner for International Patent Cooperation

November 19, 2015

UNITED STATES
PATENT AND TRADEMARK OFFICE



Overview of Global Dossier

UNITED STATES
PATENT AND TRADEMARK OFFICE



The IP5

First meeting held May 2007

Members:

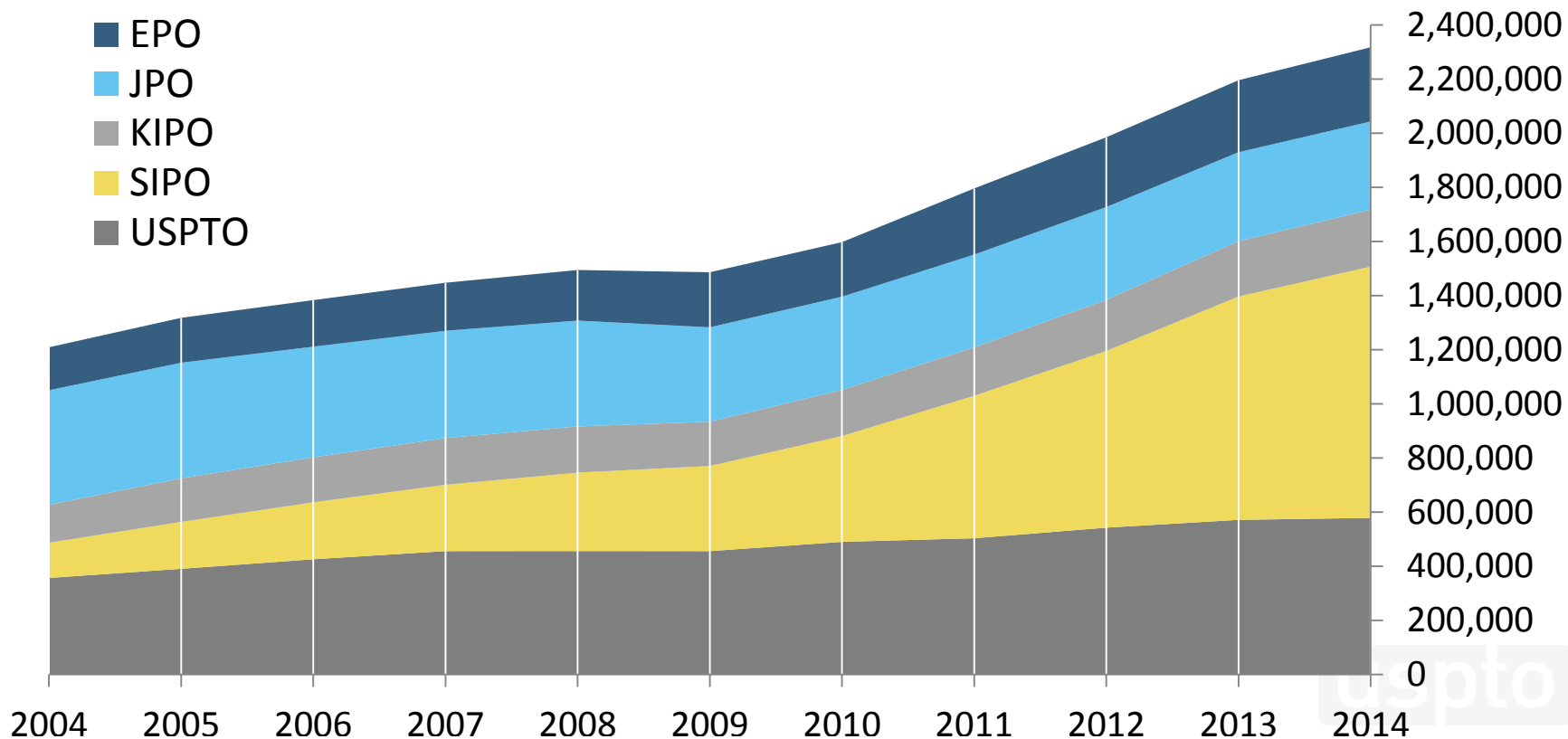
- European Patent Office (EPO)
- Japan Patent Office (JPO)
- Korean Intellectual Property Office (KIPO)
- State Intellectual Property Office of the People's Republic of China (SIPO)
- United States Patent & Trademark Office (USPTO)

fiveIPoffices

European Patent Office /// Japan Patent Office ///
Korean Intellectual Property Office /// State Intellectual
Property Office of the People's Republic of China ///
United States Patent and Trademark Office

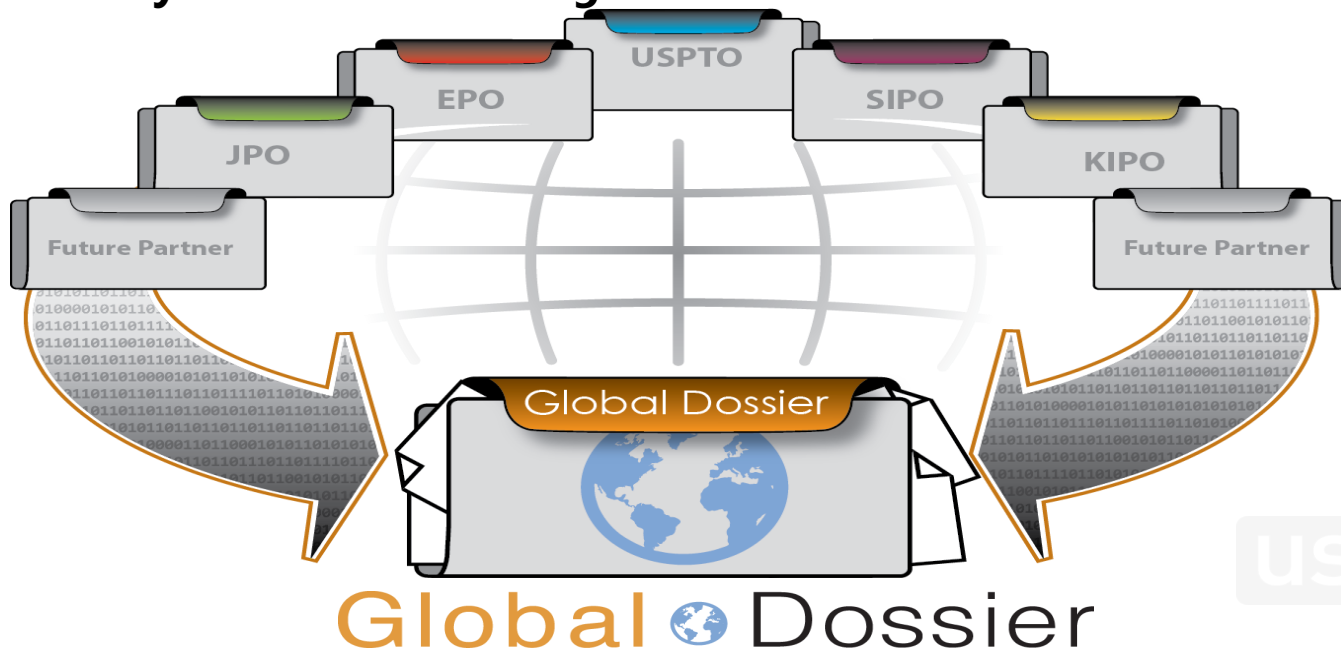
uspto

Evolution of filings at the IP5 (2004-2014)



Global Dossier

Global Dossier is a set of business services modernizing the global patent system and delivering benefits to all stakeholders



Global Dossier Task Force

Members:

– **IP5 Offices**

- United States Patent and Trademark Office (USPTO)
- European Patent Office (EPO)
- Japan Patent Office (JPO)
- Korean Intellectual Property Office (KIPO)
- State Intellectual Property Office of the People's Republic of China (SIPO)

– **Industry IP5 Members**

- American Intellectual Property Law Association (AIPLA)
- Intellectual Property Owners Association (IPO)
- Japan Intellectual Property Association (JIPA)
- Korea Intellectual Property Association (KINPA)
- Patent Protection Association of China (PPAC)
- BUSINESSEUROPE

– **World Intellectual Property Organization (WIPO)**



Global Dossier First Release Demo

UNITED STATES
PATENT AND TRADEMARK OFFICE



Global Dossier Family List

The screenshot shows the USPTO Global Dossier website. At the top, there is a navigation bar with links for Home, Public Pair, Common Citation Document, Current Service Status, Service Hours, Help, and Email Us. Below this is a search bar with a dropdown for Office (set to US) and a dropdown for Type (set to Application). A search box contains the text 'Ex: XXnnnnnn'. A blue box highlights the search button, and a blue arrow points to it with the text 'Enter number'. Another blue arrow points to the Office dropdown, which is expanded to show a list of countries: US, CN, EP, KR, and JP. A third blue arrow points to the Type dropdown, which is also expanded to show a list of application types: Application, Application, Pre-grant Publication, and Patent. The main content area features a 'Welcome to Global Dossier' message, followed by sections for 'Global Dossier Public Access' and 'Service Hours'.

Office: **US** Type: **Application** Ex: XXnnnnnn

Office: US, CN, EP, KR, JP

Type: Application, Application, Pre-grant Publication, Patent

Welcome to Global Dossier

Global Dossier Public Access

The first service being provided by the Global Dossier Initiative is a secure, online access to the file histories of related applications from participating IP Offices, which currently include the IP5 Offices.

By using this service, users can see the patent family for a specific application, containing all related applications filed at participating IP Offices, along with the dossier, classification, and citation data for these applications. This service also provides Office Action Indicators to help users identify applications that contain office actions, a Collections View for saving documents and applications for review later on in the session, and the ability to download the documents in an application.

Service Hours

Global Dossier users will be able to view the scheduled service hours for each IP5 office, including scheduled outages due to holidays and maintenance.

To view the scheduled hours of availability, users can select the **Service Hours** link on the top right corner of the website. In addition, any current scheduled outages for one or more offices will also be displayed on top of the homepage as a reminder for the users.

Users may also verify the availability of application data from each office by selecting the **Current Service Status** link on the top right side of the website.

The footer of the USPTO website. It features the USPTO logo on the left, followed by the text 'UNITED STATES PATENT AND TRADEMARK OFFICE'. Below this, there are four columns of links: 'BROWSE BY TOPIC' (Patents, Trademarks, Learning & Resources, About the USPTO, Glossary, Careers), 'ABOUT THIS SITE' (Accessibility, Privacy Policy, Terms of Use, Security, Systems Status, Site Map), 'USPTO BACKGROUND' (Federal Activity Inventory Reform Act (FAIR), USPTO Budget and Performance, Freedom of Information Act, Information Quality Guidelines), and 'FEDERAL GOVERNMENT' (Regulations.gov, StopFakes.gov, USA.gov, Department of Commerce, Strategy Targeting Organized Piracy). On the right side, there is a circular seal of the United States Patent and Trademark Office, Department of Commerce.

uspto UNITED STATES PATENT AND TRADEMARK OFFICE

BROWSE BY TOPIC

- Patents
- Trademarks
- Learning & Resources
- About the USPTO
- Glossary
- Careers

ABOUT THIS SITE

- Accessibility
- Privacy Policy
- Terms of Use
- Security
- Systems Status
- Site Map

USPTO BACKGROUND

- Federal Activity Inventory Reform Act (FAIR)
- USPTO Budget and Performance
- Freedom of Information Act
- Information Quality Guidelines

FEDERAL GOVERNMENT

- Regulations.gov
- StopFakes.gov
- USA.gov
- Department of Commerce
- Strategy Targeting Organized Piracy

Global Dossier Family List

uspto Global Dossier

Home Public Pair Common Citation Document

Office: US Type: Application Search: 13565455

Current Service Status Service Hours Help Email Us

US 13565455 9 Members in Patent Family (8 currently shown)

IP Office Type

- ☒ All IP5 Offices
- ☒ EPO
- ☒ SIPO
- ☒ KIPO
- ☒ JPO
- ☒ USPTO
- ☐ Non-IP5 Offices

Filtering

US 13565455 9 Members in Patent Family (8 currently shown)

Sorting indicator

Office Action Indicator

Office	Application	Applicant	Title	App. Date	Priority #	Pub. #	Pub. Date	Action
US	PCT/US09/54677	1) Applied Materials, Inc.	Laser material removal methods and apparatus	08/21/2009	US 9204408	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP						EP 2329518 A2	06/08/2011	(1) Add to ★
US						US 20100055901 A1 US 8258426 B2	03/04/2010 09/04/2012	(1) Add to ★
CN	201310590403	4) Eberspacher, Chris 1) APPLIED MATERIALS, INC.	Laser material removal methods and apparatus	08/21/2009	US 9204408	CN 103537811 A	01/29/2014	(1) Add to ★
CN	200980133793	1) The Applied Materials,	Laser material removal methods and apparatus	08/21/2009	US 9204408 US PCT/US09/54677	CN 102132378 A CN 102132378 B	07/20/2011 12/11/2013	(2) Add to ★
KR			LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408	KR 20110059724 A	06/03/2011	Add to ★
JP				08/21/2009	US 9204408	JP 2012501249 A	01/19/2012	
US			LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/02/2012	US 9204408 US PCT/US09/54677	US 20120295440 A1 US 8549650 B2	11/22/2012 10/26/2013	(2) Add to ★

uspto UNITED STATES PATENT AND TRADEMARK OFFICE

BROWSE BY TOPIC

- Patents
- Trademarks
- Learning & Resources
- About the USPTO
- Glossary
- Careers
- Contact Us

Terms of Use

- Security
- Systems Status
- Site Map

USPTO BACKGROUND

- Federal Activity Inventory Reform Act (FAIR)
- USPTO Budget and Performance
- Freedom of Information Act
- Information Quality Guidelines

FEDERAL GOVERNMENT

- Regulations.gov
- StopFakes.gov
- USA.gov
- Department of Commerce
- Strategy Targeting Organized Piracy

DEPARTMENT OF COMMERCE

Global Dossier Family List

uspto Global Dossier

HomePublic PairCommon Citation Document

Current Service StatusService HoursHelpEmail Us

Office: US Type: Application 13565455

Collections 0History 1

US 13565455 9 Members in Patent Family (8 currently shown)

Download list of patent family members

IP Office Type	Office	Application	Applicant	Title	Pub. No.	Pub. Date	Action
<input checked="" type="checkbox"/> All IP5 Offices	US	PCT/US09/54677 Refresh Dossier			WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
<input checked="" type="checkbox"/> EPO	EP	09811971 View Dossier	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	US 9204408 US PCT/US09/54677	06/08/2011	(1) Add to ★
<input checked="" type="checkbox"/> SIPO	US	12545488 View Dossier	1) Zhang, Zhenhua 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	US 2010055901 A1 US 8258426 B2	03/04/2010 09/04/2012	(1) Add to ★
<input checked="" type="checkbox"/> KIPO	CN	201310590403 View Dossier	1) APPLIED MATERIALS, INC.	Laser material removal methods and apparatus	CN 103537811 A	01/29/2014	(1) Add to ★
<input checked="" type="checkbox"/> JPO	CN	200980133793 View Dossier	1) The Applied Materials,	Laser material removal methods and apparatus			
<input checked="" type="checkbox"/> USPTO	KR	20117006576 View Dossier	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS			
<input type="checkbox"/> Non-IP5 Offices	JP	2011525114 Refresh Dossier					
	US	13565455 View Dossier	1) ZHANG, ZHENHUA 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS			

US PATENT & TRADEMARK OFFICE PATENT APPLICATION FULL TEXT AND IMAGE DATABASE

[Help](#) [Home](#) [Boolean](#) [Manual](#) [Number](#) [PTOL](#)
[Full List](#) [Bottom](#)
[View Shopping Cart](#) [Add to Shopping Cart](#)
[Images](#)

(1 of 1)

United States Patent Application

Kind Code
Zhang; Zhenhua ; et al.

2010055901
A1
March 4, 2010

LASER MATERIAL REMOVAL METHODS AND APPARATUS

Abstract

Embodiments of the present invention generally provide methods and apparatus for material removal using lasers in the fabrication of solar cells. In one embodiment, an apparatus is provided that precisely removes portions of a dielectric layer deposited on a solar cell substrate according to a desired pattern and deposits a conductive layer over the patterned dielectric layer. In one embodiment, the apparatus also removes portions of the conductive layer in a desired pattern. In certain embodiments, methods for removing a portion of a material via a laser without damaging the underlying substrate are provided. In one embodiment, the intensity profile of the beam is adjusted so that the difference between the maximum and minimum intensity within a spot formed on a substrate surface is reduced to an optimum range. In one example, the substrate is positioned such that the peak intensity at the center versus the periphery of the substrate is lowered. In one embodiment, the pulse energy is improved to provide thermal stress and physical lift-off of a desired portion of a dielectric layer.

Inventors: Zhang; Zhenhua; (Newark, CA); Rana; Virendra V.S.; (Los Gatos, CA); Shah; Vinay K.; (San Mateo, CA); Eberspacher; Chris; (Palo Alto, CA)
Correspondence Address: PATTERSON & SHERIDAN, LLP - APPM/TX
3040 POST OAK BOULEVARD, SUITE 1500
HOUSTON
TX
77056
US
Assignee: APPLIED MATERIALS, INC.
Santa Clara
CA

Family ID: 41726084
Appl. No.: 12/545488
Filed: August 21, 2009

Publication Link

Related U.S. Patent Documents

uspto

UNITED STATES
PATENT AND TRADEMARK OFFICE

BROWSE BY TOPIC

[Patents](#)
[Trademarks](#)
[Learning & Resources](#)
[About the USPTO](#)
[Glossary](#)
[Careers](#)
[Contact Us](#)

ABOUT THIS SITE

[Accessibility](#)
[Privacy Policy](#)
[Terms of Use](#)
[Security](#)
[Systems Status](#)
[Site Map](#)

Global Dossier Quick View

The screenshot displays the USPTO Global Dossier interface. At the top, the 'uspto Global Dossier' header is visible, along with navigation links for 'Home', 'Public Pair', 'Common Citation Document', 'Current Service Status', 'Service Hours', 'Help', and 'Email Us'. The main search area shows 'Office: US' and 'Type: Application' with a search box containing '13565455'. Below this, the 'US 13565455' patent is listed with 9 members in its family (8 currently shown). The 'IP Office Type' sidebar on the left includes checkboxes for 'All IPS Offices' and 'Non-IPS Offices', with sub-options for EPO, SIPO, KIPO, JPO, and USPTO. The main table lists patent entries with columns for Office, Application, Applicant, Title, App. Date, Priority #, Pub. #, Pub. Date, and Action. A 'Quick View Display' box highlights the 'Claims (ORIGINAL)', 'Argument (TRANSLATED)', and 'Argument (ORIGINAL)' documents. A 'Collapse/Expand Quick View' button is located at the bottom left. On the right, a 'First Office Action (TRANSLATED)' window is open, showing the title 'The State Intellectual Property Office of People's Republic of China' and the application number '200233'. The text of the first office action is displayed below.

uspto Global Dossier

Home Public Pair Common Citation Document Current Service Status Service Hours Help Email Us

Office: US Type: Application 13565455

US 13565455 9 Members in Patent Family (8 currently shown)

IP Office Type

- ☒ All IPS Offices
 - ☒ EPO
 - ☒ SIPO
 - ☒ KIPO
 - ☒ JPO
 - ☒ USPTO
- ☐ Non-IPS Offices

Office	Application	Applicant	Title	App. Date	Priority #	Pub. #	Pub. Date	Action
US	PCT/US09/54677			08/21/2009	US 61092044	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP	09811971	1) Applied Materials, Inc.	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 61092044 US PCT/US09/54677	EP 2329518 A2	06/08/2011	(1) Add to ★

DATE DOCUMENT DESCRIPTION OPTIONS

- Mar 11, 2015 CDS Clean up - amended data concerning the representative of the applicant (Association) ...
- Apr 28, 2015 Claims (ORIGINAL) ...
- Apr 28, 2015 Argument (TRANSLATED) ...
- Apr 28, 2015 Argument (ORIGINAL) ...

All Documents Classification and Citation

Quick View Display

Collapse/Expand Quick View

First Office Action (TRANSLATED)

The State Intellectual Property Office of People's Republic of China

200233
上海桂平路435号 上海专利商标事务所有限公司
陆嘉

Issuing Date:

Application No. or Publication Issue No.:
No. 201310590403.1

Applicant Patentee: APPLIED MATERIALS, INC.

Title of Invention: Laser material removal methods and apparatus

First Office Action

1. Upon the request of substantive examination of the applicant, in accordance with Article 35.1 of the Patent Law, the State Intellectual Property Office performs the substantive examination for the aforesaid application for a patent for invention.

In accordance with Article 35.2 of the Patent Law, the State Intellectual Property Office proceeds to examine the aforesaid application for a patent for invention as to its substance on its own initiative.

2. The applicant requests on the basis of:

Global Dossier Collections

The screenshot displays the USPTO Global Dossier interface. The top navigation bar includes links for Home, Public Pair, Common Citation Document, Current Service Status, Service Hours, and Help. The main header shows the USPTO logo and the text "Global Dossier".

The left sidebar contains the "IP Office Type" section with checkboxes for All IP5 Offices (checked), EPO, SIPO, KIPO, JPO, USPTO, and Non-IP5 Offices.

The main content area displays patent information for US 13565455, including a table of documents with columns for Office, Application, Applicant, Title, and App. Date. The table lists documents for US, EP, and CN offices, including applications PCT/US09/54677 and 09811971, and US 12545488 and 201310590403.

Annotations highlight key features:

- A blue arrow points to the "Open Document in New Window" and "Download Document" buttons in the document description table.
- A blue arrow points to the "Add to Collections" button in the document description table.
- A blue arrow points to the "Add Application to Collections" button in the Collections panel.

The right sidebar shows the "Collections" panel, which lists various document types such as Specification, Oath or Declaration filed, Application Data Sheet, Transmittal of New Application, Drawings-only black and white line drawings, Abstract, Claims, EFS Acknowledgment Receipt, Authorization to access Appl. by Trilateral Office, Filing Receipt, Notice to File Missing Parts, Fee Worksheet (SB06), Applicant Response to Pre-Exam Formalities Notice, Fee Worksheet (SB06), Oath or Declaration filed, EFS Acknowledgment Receipt, Power of Attorney, and Assignee showing of ownership per 37 CFR 3.73. Each entry has an "Add to ★" button.

Global Dossier History

uspto Global Dossier

Home Public Pair Common Citation Document Current Service Status Service Hours Help

Office US Type Application 13565455 Q

★ Collections 0 History 1

US 13565455 9 Members in Patent Family (8 currently shown)

IP Office Type

- ☒ All IP5 Offices
- ☒ EPO
- ☒ SIPO
- ☒ KIPO
- ☒ JPO
- ☒ USPTO
- ☐ Non-IP5 Offices

Office	Application	Applicant	Title	App. Date	Priority #	Pub. #	Pub. Date	Action
US	PCT/US09/54677 Refresh Dossier			08/21/2009	US 9204408	WO 2010027712 A2 WO 2010027712 A3	03/11/2010 05/14/2010	
EP	09811971	1) Applied Materials, Inc.,	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408 US PCT/US09/54677			
<div>DATE DOCUMENT DESCRIPTION VIEW MORE</div> <div>Mar 11, 2015 CDS Clean up - amended data concerning the representative of the applicant (Association) ...</div> <div>Jul 23, 2014 Refund of fees ...</div> <div>Jul 23, 2014 Refund of fees ...</div> <div>All Documents Classification and Citation</div>								
US	12545488	1) Zhang, Zhenhua 2) Rana, Virendra V.S. 3) Shah, Vinay K. 4) Eberspacher, Chris	LASER MATERIAL REMOVAL METHODS AND APPARATUS	08/21/2009	US 9204408			
<div>DATE DOCUMENT DESCRIPTION VIEW MORE</div> <div>Aug 15, 2012 Issue Notification ...</div> <div>Aug 1, 2012 EFS Acknowledgment Receipt ...</div> <div>Aug 1, 2012 Fee Worksheet (SB06) ...</div> <div>All Documents Classification and Citation</div>								
CN	201310590403	1) APPLIED MATERIALS, INC.,	Laser material removal methods and apparatus	08/21/2009	US 9204408			
<div>DATE DOCUMENT DESCRIPTION VIEW MORE</div> <div>Apr 28, 2015 Claims (ORIGINAL) ...</div> <div>Apr 28, 2015 Argument (TRANSLATED) ...</div> <div>Apr 28, 2015 Argument (ORIGINAL) ...</div> <div>All Documents Classification and Citation</div>								
CN	200980133793	1) The Applied Materials,	Laser material removal methods and apparatus	08/21/2009	US 9204408 US PCT/US09/54677	CN 102132378 A CN 102132378 B	07/20/2011 12/11/2013	(2) Add to ★

History

Application

US 13565455
EP 09811971

Publication

US 20070155322

History of viewed applications

Global Dossier - Dossier View

uspto

Global Dossier

Home

Public Pair

Common Citation Document

Application Number

US 12545488

Patent Family

All Documents

Classification & Citation

Current Service Status

Service Hours

Help

Email Us

Collections

0

History

2

US 12545488 (US 20100055901 A1, US 8258426 B2) 67 documents

Group

Title

Date

Code

Options

unknown

Issue Notification

08/15/2012

ISSUE.NTF

...

4

Issue Fee Payment (PTO-85B)

08/01/2012

IFEE

...

5

Fee Worksheet (SB06)

08/01/2012

...

2

EFS Acknowledgment Receipt

08/01/2012

...

102

Search information including classification, databases and other search related notes

07/06/2012

...

101

List of References cited by applicant and considered by examiner

07/06/2012

...

101

List of References cited by applicant and considered by examiner

07/06/2012

...

101

List of References cited by applicant and considered by examiner

07/06/2012

1449

...

5

Examiner's search strategy and results

07/06/2012

SRNT

...

101

List of References cited by applicant and considered by examiner

07/06/2012

1449

...

101

List of references cited by examiner

07/06/2012

802

...

2, 23

Notice of Allowance and Fees Due (PTOL-85)

07/06/2012

NOA

...

5

Index of Claims

07/06/2012

FWCLM

...

102

Issue Information including classification, examiner, name, claim, renumbering, etc.

07/06/2012

IIFW

...

4

Bibliographic Data Sheet

07/06/2012

BIB

...

5

Examiner's search strategy and results

07/06/2012

SRNT

...

5

Fee Worksheet (SB06)

04/27/2012

WFEE

...

2

EFS Acknowledgment Receipt

04/27/2012

N417

...

4

Response to Election / Restriction Filed

04/27/2012

ELC

...

4

Applicant Arguments/Remarks Made in an Amendment

04/27/2012

REM

...

1


Claims

04/27/2012

CLM

...

Notice of Allowance and Fees Due (PTOL-85)

UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
United States Patent and Trademark Office
Address: COMMISSIONER, P.O. BOX 773
P.O. Box 1470
Alexandria, Virginia 22313-1480
www.uspto.gov

NOTICE OF ALLOWANCE AND FEE(S) DUE

44257 7590 07/06/2012

PATTERSON & SHERIDAN, LLP - - APPM/TX

3040 POST OAK BOULEVARD, SUITE 1500

HOUSTON, TX 77056

EXAMINER

TRINEL, MICHAEL, MANSH

ART UNIT

PAPER NUMBER

2822

DATE MAILED: 07/06/2012

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
12/545,488	08/21/2009	Zhenhua Zhang	013818/ES/SOLAR-C/ES/ONG	1445
TITLE OF INVENTION: LASER MATERIAL REMOVAL METHODS AND APPARATUS				

APPL. TYPE	SMALL ENTITY	ISSUE FEE DUE	PUBLICATION FEE DUE	PREV. PAID ISSUE FEE	TOTAL FEES DUE	DATE DUE
nonprovisional	NO	\$1740	\$300	\$0	\$2040	10/09/2012

THE APPLICATION IDENTIFIED ABOVE HAS BEEN EXAMINED AND IS ALLOWED FOR ISSUANCE AS A PATENT. PROSECUTION ON THE MERITS IS CLOSED. THIS NOTICE OF ALLOWANCE IS NOT A GRANT OF PATENT RIGHTS. THIS APPLICATION IS SUBJECT TO WITHDRAWAL FROM ISSUE AT THE INITIATIVE OF THE OFFICE OR UPON PETITION BY THE APPLICANT. SEE 37 CFR 1.313 AND MPEP 1308.

THE ISSUE FEE AND PUBLICATION FEE (IF REQUIRED) MUST BE PAID WITHIN THREE MONTHS FROM THE MAILING DATE OF THIS NOTICE OR THIS APPLICATION SHALL BE REGARDED AS ABANDONED. THIS STATUTORY PERIOD CANNOT BE EXTENDED. SEE 35 U.S.C. 151. THE ISSUE FEE DUE INDICATED ABOVE DOES NOT REFLECT A CREDIT FOR ANY PREVIOUSLY PAID ISSUE FEE IN THIS APPLICATION. IF AN ISSUE FEE HAS PREVIOUSLY BEEN PAID IN THIS APPLICATION (AS SHOWN ABOVE), THE RETURN OF PART B OF THIS FORM WILL BE CONSIDERED A REQUEST TO REAPPLY THE PREVIOUSLY PAID ISSUE FEE TOWARD THE ISSUE FEE NOW DUE.

HOW TO REPLY TO THIS NOTICE:

I. Review the SMALL ENTITY status shown above.

If the SMALL ENTITY is shown as YES, verify your current SMALL ENTITY status:

A. If the status is the same, pay the TOTAL FEE(S) DUE shown above.

B. If the status above is to be removed, check box 5b on Part B - Fee(s) Transmittal and pay the PUBLICATION FEE (if required) and twice the amount of the ISSUE FEE shown above, or

If the SMALL ENTITY is shown as NO:

A. Pay TOTAL FEE(S) DUE shown above, or

B. If applicant claimed SMALL ENTITY status before, or is now claiming SMALL ENTITY status, check box 5a on Part B - Fee(s) Transmittal and pay the PUBLICATION FEE (if required) and 1/2 the ISSUE FEE shown above.

II. PART B - FEE(S) TRANSMITTAL, or its equivalent, must be completed and returned to the United States Patent and Trademark Office (USPTO) with your ISSUE FEE and PUBLICATION FEE (if required). If you are charging the fees to your deposit account, section "4b" of Part B - Fee(s) Transmittal should be completed and an extra copy of the form should be submitted. If an equivalent of Part B is filed, a request to reapply a previously paid issue fee must be clearly made, and delays in processing may occur due to the difficulty in recognizing the paper as an equivalent of Part B.

III. All communications regarding this application must give the application number. Please direct all communications prior to issuance to

Global Dossier Classification Data

uspto Global Dossier

HomePublic PairCommon Citation Document

Application NumberEP 09811971Patent FamilyAll DocumentsClassification and Citation

Current Service StatusService HoursHelp

★ Collections 0🕒 History 3

Classification Data ⓘ ⚙

IPC8

H01L 21/027

H01L 31/042

CPC ⓘ

B23K 26/0853

B23K 26/06

B23K 2201/40
B23K 26/0807
B23K 26/4075
B23K 26/03

H01L 31/18
B23K 26/0635
H01L 31/022425

No matching citation data found.

B23K 26/0846

....

{for moving elongated workpieces longitudinally, e.g. wire or strip material}



B23K 26/0853

...

{Devices involving movement of the workpiece in at least in two axial directions, e.g. in a plane}

B23K 26/0861

....

{in at least in three axial directions}

Classification Description

Global Dossier Citations

uspto Global Dossier

HomePublic PairCommon Citation Document

About UsCareersContact Us

Current Service StatusService HoursHelp

Application NumberUS 12545488Patent FamilyAll DocumentsClassification and Citation

★ Collections 0🕒 History 3

Classification Data ⓘ ⤴

IPC8

B23K 26/38B05C 11/00H01L 21/30

Citation Data ⓘ ⤴

CITED BY	CITED IN	PUBLICATION/PATENT NUMBER ⓘ
applicant		US20090162972/A1
applicant		US20100055901/A1
applicant		US20100067020/A1
examiner		US20070232009/A1
examiner		US20090321189/A1
examiner		US6300593/B1
examiner		US7259321/B1
examiner		US7353076/B1
examiner		US7880155/B1
applicant		US20060196536/A1
applicant		US20010037823/A1
applicant		US20020117199/A1
applicant		US20030044539/A1
applicant		US20030129810/A1
applicant		US20060103371/A1
applicant		US20080012189/A1
applicant		US20080105295/A1
applicant		US20080115827/A1
applicant		US20090000108/A1
applicant		US20090077805/A1
applicant		US4144493/B1

[View Full Patent Family](#)[View Application Dossier](#)[View Publication](#)

Global Dossier Availability

The screenshot displays the USPTO Global Dossier website. At the top, a navigation bar includes links for Home, Public Pair, Common Citation Document, Current Service Status, Service Hours, Help, and Email Us. A blue box highlights the 'Current Outages' section, which states: 'JPO OPD Dossier Access Services are down for scheduled maintenance'. Below this, a search bar is visible with 'Office' set to 'US' and 'Type' set to 'Application'. A blue arrow points from the 'Current Outages' box to a larger, detailed view of the outage message. Another blue arrow points from the 'Service Hours' link in the navigation bar to a detailed 'Service Hours' table. A third blue arrow points from the 'Check Availability' button in the 'Service Availability Status' modal to the same button. The 'Service Availability Status' modal shows the status for USPTO, with a table indicating that Patent Family, Dossier Content, and Classification & Citation services are all 'UP' for both Actual and Scheduled access. The 'Service Hours' table shows scheduled outage hours in red text with an asterisk, indicating service is down from 23:00 to 23:15 on Mondays, Tuesdays, Wednesdays, Thursdays, and Fridays.

Current Outages

- JPO OPD Dossier Access Services are down for scheduled maintenance

[View More](#)

Service Availability Status

Offices

☒ USPTO ☐ EPO ☐ JPO ☐ KIPO ☐ SIPO

[Check Availability](#)

SERVICE AVAILABILITY STATUS FOR -- USPTO

	Patent Family	Dossier Content	Classification & Citation
Actual	UP	UP	UP
Scheduled	UP	UP	UP

Service Hours

USPTO EPO JPO KIPO SIPO

The Scheduled Outage Hours (EST/EDT) are displayed in red text indicated by an asterisk (*).
The scope of available document range coverage for EPO is from January 6, 1978 onwards.

	Patent Family Service	Dossier Content Service	Classification & Citation Service
MONDAY	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
TUESDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
WEDNESDAY	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 11:00 11:00 - 12:00* 12:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
THURSDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
FRIDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
SATURDAY	00:00 - 23:00 23:00 - 23:59*	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59
SUNDAY	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59	00:00 - 23:59	00:00 - 23:00 23:00 - 23:15* 23:15 - 23:59

User Feedback

- Timeline view for applications
- Providing access to foreign publications
- Enhanced OA indicator
- Exchanging citation data between Offices

Global Dossier First Release

Coming November 2015:

- Access to all available information about applications and patents in the participating offices with the first service – Dossier access
- Applicants can efficiently track and manage related applications across jurisdictions
- Easier and less costly to perform functions associated with due diligence, technology transfer, and litigation and appeal processes.

IP5 Priorities for Global Dossier

- **USPTO – “Proof-of-Concept for Inter-Office Exchange”**
 - Sharing documents between offices including for example, prior art exchanges, bib data updates, and supporting documents. Viewed as a first step towards cross-filing
- **EPO – “Alerting”**
 - Automated mechanism whereby each office alerts all the other offices, applicants, and representatives of changes in status to an application
- **JPO – “XML”**
 - Enabling each office, and possibly applicants and representatives, to download all application-related data from applications pending in other offices in XML format
- **KIPO – “Applicant Name Standardization”**
 - An automated mechanism that will assign a single, unique name to entities with applications pending in multiple office, including in instances where those entities may have used multiple names, or variations of a single name. to identify themselves
- **SIPO -- “Legal Status”**
 - A mechanism to allow users to view the legal status of an application in another office

Benefits of Global Dossier

Cost savings - exploit more IP!

Improved patent quality

Higher value patents

Decreased time to file internationally

Increased ease of international filing

Global  Dossier

uspto

Questions and Comments

Shira Perlmutter

Chief Policy Officer and Director of International Affairs

(571) 272-9300

Shira.Perlmutter@USPTO.GOV

Mark Powell

Deputy Commissioner for International Patent Cooperation

(571) 272-8800

Mark.Powell@USPTO.GOV

